

<b>Notice of References Cited</b>	Application/Control No. 10/683,858	Applicant(s)/Patent Under Reexamination VASHCHENKO ET AL.	
	Examiner Michael K. Luhrs	Art Unit 2824	Page 1 of 3

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	B	US-5,516,705	05-1996	Webb et al.	438/133
	C	US-6,555,894	04-2003	Beasom, James D.	257/593
	D	US-6,642,558	11-2003	Letavic et al.	257/219
	E	US-5,801,836	09-1998	Bakowski et al.	257/487
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	H	US-6,355,508	03-2002	Porter et al.	438/140
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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<b>Notice of References Cited</b>	Application/Control No. 10/683,858	Applicant(s)/Patent Under Reexamination VASHCHENKO ET AL.	
	Examiner Michael K. Luhrs	Art Unit 2824	Page 2 of 3

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	Examiner Michael K. Luhrs	Art Unit 2824	Page 3 of 3

**U.S. PATENT DOCUMENTS**

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	L	US-			
	M	US-			

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